Microfabrication in optoelectronics (Opti-677)

Instructor: Mahmoud Fallahi

2 credit course

This course is intended to give a broad understanding of various microfabrication techniques used in photonic and optoelectronic components. It covers epitaxial growth, lithography and processing steps of compound semiconductors frequently used in micro/nano-fabrication of optical and optoelectronic devices. Fabrication of waveguides and laser diodes and various integration techniques are also discussed. The following topics are covered.

- 1. Introduction to Microfabrication
 - Clean room and its operation
 - Sources of Contamination
- 2. Lithography
 - Photolithography
 - Resist processing
 - Exposure
 - Lift-off process
- 3. Growth techniques:
 - MBE
 - MOCVD
 - CBE
- 4. Metallization
 - Ohmic contact
 - Schottky contacts
 - Annealing
- 5. Etching techniques
 - Wet etching
 - Dry etching
 - What to choose
- 6. Holography, EBL, FIB
- 7. Passivation and packaging
- 8. Optoelectronic Fabrication
 - Waveguides
 - Laser diodes
 - OEIC
- 9. Integration Techniques

Microfabrication in Optoelectronics

Opti-677;

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Reference Books

Technology of Quantum Devices: Manijeh Razeghi

Handbook of Compound Semiconductors: Holloway & McGuire

Semiconductor Lithography: Moreau

Course Grading

Classroom Attendance/ Discussion	20%
Exam	40%
Project 2	40%